

Title (en)

POLISHING DEVICE AND POLISHING METHOD

Title (de)

POLIERVORRICHTUNG UND POLIERVERFAHREN

Title (fr)

DISPOSITIF DE POLISSAGE ET PROCÉDÉ DE POLISSAGE

Publication

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Application

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Abstract (en)

It is an objective of the present invention to provide a polishing device and a polishing method that allows for polishing of workpieces having various contours. The polishing device includes a motor movement mechanism (33) and a second motor (30) that rotates a workpiece (K). The motor movement mechanism (33) moves the workpiece (K) in a direction tangential to a radially outer circumferential surface of a polishing member (10) and moves the workpiece (K) in a direction orthogonal to a rotational axis of the polishing member (10).

IPC 8 full level

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